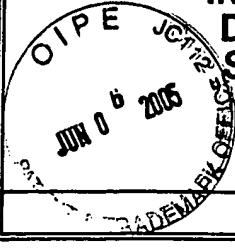


**INFORMATION
DISCLOSURE
STATEMENT**



SHEET 1 OF 1

| Complete if known | |
|-----------------------------------|--|
| Application Number: 10/076,858 | |
| Filing Date: February 14, 2002 | |
| First Named Inventor: Steinberg | |
| Group Art Unit: 1775 | |
| Examiner Name: Stephen J. Stein | |
| Attorney Docket Number: R&H 03-19 | |

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| EXAMINER'S INITIALS | CITE NO. | PATENT NUMBER | ISSUE DATE MM-DD-YYYY | FIRST NAMED INVENTOR |
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| EXAMINER'S INITIALS | CITE NO. | DOCUMENT NUMBER | COUNTRY OR REGION | DATE OF PUBLICATION MM-DD-YYYY | FIRST NAMED INVENTOR OR APPLICANT |
|---------------------|----------|-----------------|-------------------|-----------------------------------|-----------------------------------|
| | | | | | |

OTHER PRIOR ART - NON-PATENT DOCUMENTS

| | | |
|---------------------|----------|---|
| EXAMINER'S INITIALS | CITE NO. | Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item(book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published |
| | | Nijdam, et al. "Etching of silicon in alkaline solutions: a critical look at the {111} minimum," MESA |
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| EXAMINER'S SIGNATURE | | DATE CONSIDERED |
|----------------------|--|--------------------|

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP §609. Draw a line through citation if citation not in conformance and reference not considered. Include a copy of this form with next communication to applicant.